



OPTIX GAS SENSOR



Optix is a multi-purpose and highly robust instrument for gas sensing in any vacuum environment, providing automatic operation and real-time species detection.

Based upon the Remote Plasma Emission Monitoring (RPEM) method, Optix caters for most industrial vacuum processes without a requirement for differential pumping, functioning at process pressures from 0.5 to 10^{-7} mbar.

KEY FEATURES

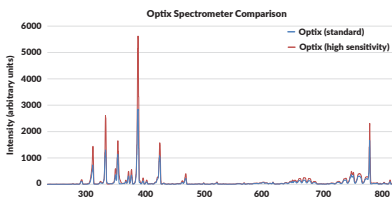
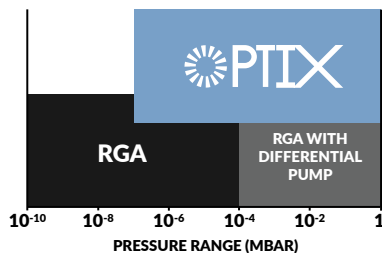
1. Wide pressure range, operating directly at process pressures from 0.5 to 10^{-7} mbar
2. High sensitivity spectrometer option for applications requiring extreme sensitivity
3. Chemically-tolerant with dedicated version for ALD processes
4. Automatic operation during pump-down and switch off during venting
5. Powerful, easy-to-use software with High Dynamic Range mode for enhanced sensitivity

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OPTIX

APPLICATIONS

- Leak detection, vacuum quality, pressure sensing
- PVD, CVD, ALD
- Heat treatment
- Fusion, cannabinoids, gas sampling
- Silicon carbide etch endpoint detection



Genco Optix provides fast and robust analysis of gases within a vacuum, without differential pumping (pump required for atmospheric sampling). Unlike RGA's, the Optix detector is separated from vacuum/chemicals by an optical window that protects against operator damage.

Optix uses a remote plasma spectroscopy concept which generates a small plasma within the sensor head. A built-in high resolution spectrometer analyzes the plasma, automatically interpreting the light spectrum to provide quantitative measurement of the presence and concentration of gas within the vacuum.

The Optix spectral information and sophisticated back-end software benefit a wide range of applications. For very high chemical levels, a special plasma power mode is used to prevent electrode contamination.

SPECTROMETER OPTIONS

The latest version of Optix includes two high performance spectrometer options. As standard, the spectrometer delivers significant sensitivity improvements over the previous generation Optix unit, including up to 10x greater for Argon and Oxygen detection.

Where extreme sensitivity is required, Optix can be supplied with a high sensitivity option, which improves on the sensitivity of the standard unit by up to three times. This is important at pressures nearer to atmosphere and for processes that have high levels of background signals.

SOFTWARE

An advanced Windows user interface provides clear visualisation of the condition of the process and vacuum, and powerful tools for recording and referencing data enable easy identification of process problems.

Up to 20 gases can be monitored simultaneously, with process gas tracking that can be set up with trigger/alarm outputs.

A full, tuneable spectrum view (200-850nm) provides control of integration time for sensitivity adjustments, and automatic gas peak detection works in real-time without the need to export for data identification.

FURTHER INFORMATION

Contact: sales@genco.com or visit www.genco.com/optix

